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Dimensional Optical Metrology and Inspection for Practical Applications III

**Kevin G. Harding
Toru Yoshizawa
Song Zhang**
Editors

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Introduction

The field of Optical Metrology for Practical Applications continues to grow with the needs of the manufacturing and service communities need for more complete information. Structured light continues to be a core method for many applications with papers in this volume addressing how to reduce projector noise, improve calibration, and improve speed. Some applications covered in this volume include LED manufacturing, pipe inspection, material characterization, semiconductor manufacturing, and surface metrology. The papers presented in this volume represent many of the current and future state-of-the-art instruments of the metrology industry.

Kevin G. Harding
Toru Yoshizawa